1. Free electrons are created in the **Electron Gun** by heating a tungsten filament (Cathode)

2. Electrons are accelerated down the electron optical column by means of a high voltage potential at the **Anode**

- 3. The electron flux is shaped into a beam by the **Condenser Lenses**
- 4. The beam current is controlled by the Beam Regulation Aperture (and the condenser lenses)
- 5. The beam current is measured with, or permitted down the column by removing, the **Faraday Cup**
- 6. Beam ellipticity is corrected by the Stigmator
- 7. The beam is scanned or fixed into a probe spot by the **Final Condensing** ("objective") **Lens**
- 8. The beam impacts the sample, giving rise to various signals including secondary electrons, backscattered

electrons, x-rays, and cathodoluminescent energy. Current absorbed by the sample also can be imaged.

Secondary Electron Detector:

detects low-energy electrons liberated from near the sample surface, providing an image of sample topography

Backscattered Electron Detector

sample

Absorbed Current:Meter

images electrical conductivity

within the sample

Energy Dispersive X-ray

Analyzer:

x-rays resolved on the

basis of their energies

diffraction

crystal

scintillation counter

Wavelength Dispersive

Spectrometer

x-rays resolved by diffraction,

through a regular periodic

solid, to a gas-filled counter

detects higher-energy electrons "bounced out" of the sample, providing an image based on average atomic mass (related to

density); hence, the image is based on the compositions of constituent components